



2623
#8

PATENT
Customer No. 22,852
Attorney Docket No. 04329.2409

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Kei YOSHIKAWA et al.) Group Art Unit: 2623
Application No.: 09/662,219)
Filed: September 14, 2000)
For: PATTERN CORRECTING)
METHOD OF MASK FOR)
MANUFACTURING A)
SEMICONDUCTOR DEVICE AND)
RECORDING MEDIUM HAVING)
RECORDED ITS PATTERN)
CORRECTING METHOD)

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Technology Center 2600

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Reply to Interview Summary

In response to the Interview Summary dated January 29, 2004, Applicants respectfully submit that Claims 15-17, 19-23, 25-31, and 34-42 correspond to Species I. In view of the foregoing remarks, Applicants respectfully request the reconsideration and reexamination of this application and the timely allowance of the pending claims.

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Please grant any extensions of time required to enter this response and charge
any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: February 13, 2004

By: 

D. Kent Stier
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